



8°/Hemispherical Reflectance Calibration Certificate

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Rendered To:

Authorization: Sales Order:

Calibration Laboratory: Labsphere, Inc., Reflectance Calibration Laboratory
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Description of Calibrated Items

One gray diffuse reflectance sample, model SRT-10-100 Reflectance Target, serial number 52301-1-1

Calibration

8°/Hemispherical (8/h) Spectral Reflectance Calibration over the range 250 – 2500nm, reported at 50nm intervals

Description of Calibration

The calibration items are measured using a Perkin Elmer Lambda 900 or Lambda 950 dual beam spectrophotometer with Labsphere PELA-1000 integrating sphere reflectance accessories which perform the 8/h reflectance measurements. The instrument used for the measurement of the calibrated items is identified with an X in Table I below.

Table I Measurement Instrument and Accessory

Spectrophotometer	Lambda 900A S/N 101N 3060902	Lambda 900B, S/N: 70038	Lambda 950C SN: 950N9031801
Accessory	PELA-1000 Serial No. 05220314341	PELA-1000 Serial No. 08220625262	PELA-1000 Serial No. 1203088776
Instrument Used		X	

The integrating sphere diameter is 150 mm, the sample port diameter is 25 mm, and the interior material is Spectralon. The reference standard and sample piece are placed sequentially in the sample port of the sphere. The reference beam of the instrument acts as an auxiliary beam to correct for substitution error in the sphere. The calibration of the instrument follows the NIST method of utilizing pressed polytetrafluoroethylene (PTFE) as the reference standard¹².

Uncertainty values take into account the uncertainties of the pressed PTFE reference standard. The 8/h spectral reflectance of the sample R_s at each wavelength λ was calculated from:

Eq. 1
$$R_s = \frac{M_s - M_H}{1 - M_H} \cdot R_R$$

where:

M_s is the instrument's relative measurement of the reflectance of the calibration item

M_H is the instrument's relative measurement of the reflectance of an open sample port and measures the effect of stray light overfilling the sample port

R_R is the 8/h spectral reflectance of the pressed PTFE reference standard.

¹Wiedner V.R., and Hsia, J. J. "Reflection Properties of Pressed Polytetrafluoroethylene Powder", J.Opt.Soc.Am., Vol71, 1981, pp856-861

² Barnes, P.Y., Early, E.A., and Parr, A.C., "NIST Measurement Services: Spectral Reflectance," U.S. Dept. of Commerce, 1998.

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The instrument's relative measured reflectances, M_S and M_H are equivalent to:

Eq. 2
$$M_S = \frac{S_S}{S_R}$$

and

Eq. 3
$$M_H = \frac{S_H}{S_R}$$

where:

S_R is the signal with the reference standard in place

S_S is the signal with the calibration item in place

S_H is the signal with an open port

Therefore, the 8/h spectral reflectance of the calibration item R_S at each wavelength λ is equivalent to:

Eq. 4
$$R_S = \frac{S_S - S_H}{S_R - S_H} \cdot R_R$$

The final 8/h spectral reflectance is obtained by averaging the values from three scans.

Sources of uncertainty are:

- the 8/h spectral reflectance of the pressed PTFE reference standard
- nonuniformity across surfaces of the reference standard
- nonuniformity across the surface of the calibration item
- residual uncertainty in the correction for extraneous light
- nonlinearity of the instrument
- effect of wavelength error
- random noise in the measurements

The individual contributions to uncertainty are combined by adding in quadrature (root-sum-square). The quadrature sum is multiplied by a coverage factor (k) to generate the expanded uncertainty. The coverage factor is chosen to provide a confidence level of 95%. For effective degrees of freedom of thirty or greater, $k = 2.0$. For lower degrees of freedom a larger coverage factor is used representing the coverage factor necessary to provide a confidence level of 95% for a t-distribution with the corresponding degrees of freedom. Reference Table IV for the expended uncertainty of the calibration results.

Calibrated by:

Title: Optical Calibration Technician

Approved by:

General Information

1. The values in Table III apply only to the central 14 mm by 6 mm area of the items for measurement geometry 8/h.
2. The report of calibration may not be reproduced except in full without the written consent of this laboratory.
3. This report must not be used to claim product certification, approval, or endorsement by NVLAP, NIST, or any agency of the federal government.

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Table III. 8/h spectral reflectance R_s as a function of wavelength λ

Wavelength (nm)	Reflectance
250	0.1060
300	0.0996
350	0.0986
400	0.0984
450	0.0989
500	0.0997
550	0.1015
600	0.1027
650	0.1040
700	0.1056
750	0.1070
800	0.1084
850	0.1100
900	0.1168
950	0.1144
1000	0.1161
1050	0.1177
1100	0.1184
1150	0.1206
1200	0.1220
1250	0.1237
1300	0.1249
1350	0.1250

Wavelength (nm)	Reflectance
1400	0.1271
1450	0.1283
1500	0.1294
1550	0.1299
1600	0.1324
1650	0.1334
1700	0.1340
1750	0.1360
1800	0.1353
1850	0.1362
1900	0.1378
1950	0.1386
2000	0.1415
2050	0.1420
2100	0.1448
2150	0.1540
2200	0.1534
2250	0.150
2300	0.153
2350	0.150
2400	0.150
2450	0.163
2500	0.129

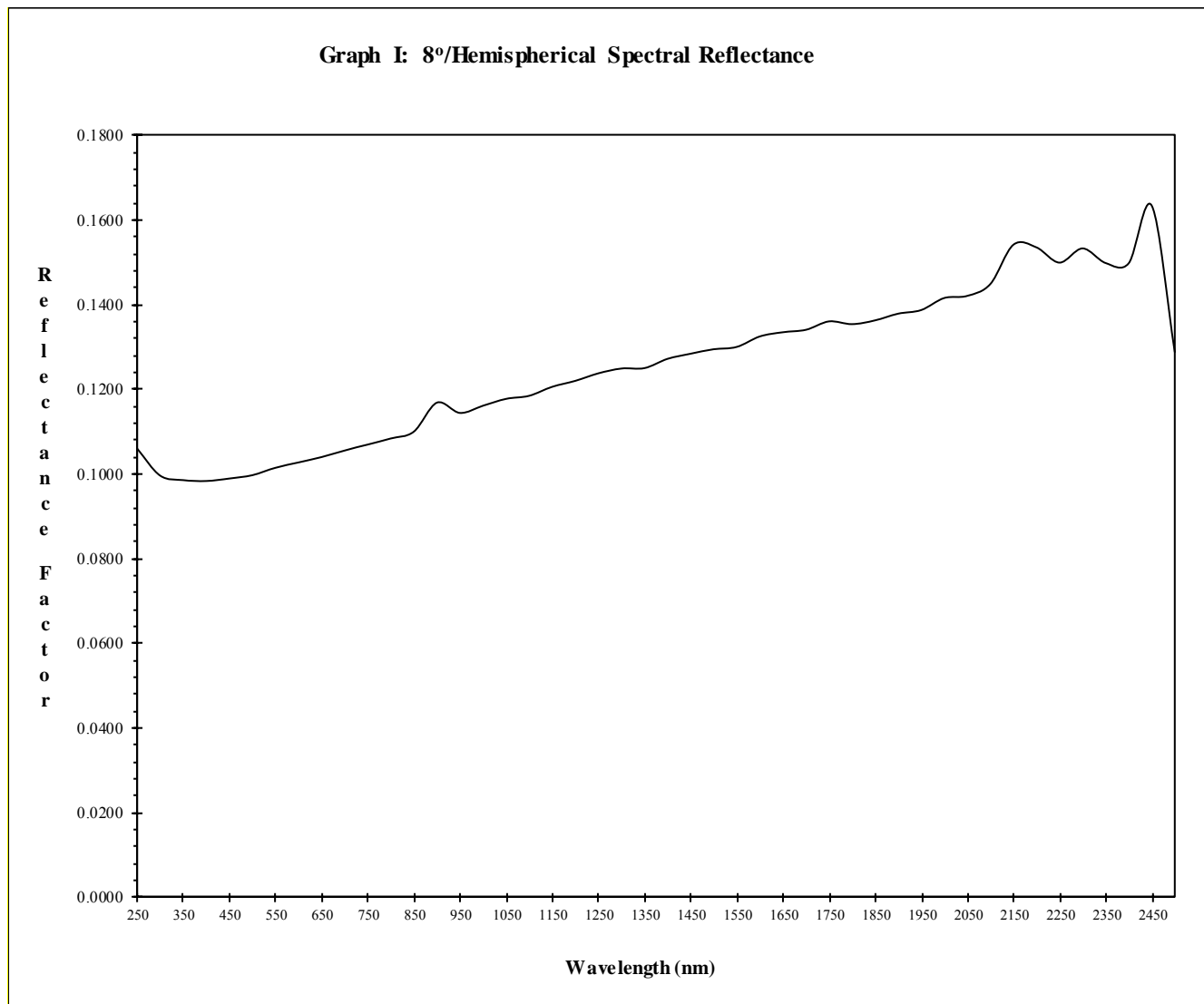
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Graph I. 8°/h spectral reflectance R_s as a function of wavelength



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Table IV Uncertainty contributions and expanded uncertainty ($k=2$) of the 8/h spectral reflectance for the measured sample

CALIBRATION AND MEASUREMENT CAPABILITIES (CMC) Notes 1,2

Measured Parameter or Device Calibrated	Range	Uncertainty ($k=2$) <small>Note 3,5</small>	Remarks
OPTICAL RADIATION			
Photometric (20/O02)			
Relative Reflectance at Wavelength Shown Below: 250 nm to 600 nm	up to 0.02 > 0.02 to 0.05 > 0.05 to 0.10 > 0.10 to 0.20 > 0.20 to 0.50 > 0.50 to 0.80 > 0.80 to 0.99	0.0016 0.0029 0.012 0.012 0.0054 0.0054 0.0053	Relative reflectance is a dimensionless quantity
601 nm to 1500 nm	up to 0.02 > 0.02 to 0.05 > 0.05 to 0.10 > 0.10 to 0.20 > 0.20 to 0.50 > 0.50 to 0.80 > 0.80 to 0.99	0.0017 0.0022 0.0025 0.0052 0.0064 0.0064 0.0049	
1501 nm to 2200 nm	up to 0.02 > 0.02 to 0.05 > 0.05 to 0.10 > 0.10 to 0.20 > 0.20 to 0.50 > 0.50 to 0.80 > 0.80 to 0.99	0.0090 0.0090 0.015 0.015 0.0099 0.0083 0.0088	
2201 nm to 2500 nm	up to 0.02 > 0.02 to 0.05 > 0.05 to 0.10 > 0.10 to 0.20 > 0.20 to 0.50 > 0.50 to 0.80 > 0.80 to 0.99	0.054 0.054 0.043 0.043 0.035 0.028 0.032	
END			

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Notes

Note 1: A Calibration and Measurement Capability (CMC) is a description of the best result of a calibration or measurement (result with the smallest uncertainty of measurement) that is available to the laboratory's customers under normal conditions, when performing more or less routine calibrations of nearly ideal measurement standards or instruments. The CMC is described in the laboratory's scope of accreditation by: the measurement parameter/device being calibrated, the measurement range, the uncertainty associated with that range (see note 3), and remarks on additional parameters, if applicable.

Note 2: Calibration and Measurement Capabilities are traceable to the national measurement standards of the U.S. or to the national measurement standards of other countries and are thus traceable to the internationally accepted representation of the appropriate SI (Système International) unit.

Note 3: The uncertainty associated with a measurement in a CMC is an expanded uncertainty using a coverage factor, $k = 2$, with a level of confidence of approximately 95 %. Units for the measurand and its uncertainty are to match. Exceptions to this occur when marketplace practice employs mixed units, such as when the artifact to be measured is labeled in non-SI units and the uncertainty is given in SI units (Example: 5 lb weight with uncertainty given in mg).

Note 3a: The uncertainty of a specific calibration by the laboratory may be greater than the uncertainty in the CMC due to the condition and behavior of the customer's device and specific circumstances of the calibration. The uncertainties quoted do not include possible effects on the calibrated device of transportation, long term stability, or intended use.

Note 3b: As the CMC represents the best measurement results achievable under normal conditions, the accredited calibration laboratory shall not report smaller uncertainty of measurement than that given in a CMC for calibrations or measurements covered by that CMC.

Note 3c: As described in Note 1, CMCs cover calibrations and measurements that are available to the laboratory's customers under *normal conditions*. However, the laboratory may have the capability to offer special tests, employing special conditions, which yield calibration or measurement results with lower uncertainties. Such special tests are not covered by the CMCs and are outside the laboratory's scope of accreditation. In this case, NVLAP requirements for the labeling, on calibration reports, of results outside the laboratory's scope of accreditation apply. These requirements are set out in Annex A.1.h. of NIST Handbook 150, Procedures and General Requirements.

Note 4: Uncertainties associated with field service calibration may be greater as they incorporate on-site environmental contributions, transportation effects, or other factors that affect the measurements. (This note applies only if marked in the body of the scope.)

Note 5: Values listed with percent (%) are percent of reading or generated value unless otherwise noted.

Note 6: NVLAP accreditation is the formal recognition of specific calibration capabilities. Neither NVLAP nor NIST guarantee the accuracy of individual calibrations made by accredited laboratories.

Note 7: See [NIST Handbook 150](#) for further explanation of these notes.